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IN THE CLAIMS:

Please cancel claim 7 without prejudice or disclaimer.

Please substitute the following amended claims for the corresponding original claims. A marked copy of the claim amendments is attached hereto.

1. (amended seven times) A process chamber for processing a substrate in a process gas and reducing emissions of hazardous gas to the environment, the process chamber comprising:
 - (a) a support capable of supporting the substrate;
 - (b) a gas distributor capable of introducing process gas into the process chamber;
 - (c) a gas activator capable of activating the process gas to perform a process in the process chamber thereby forming effluent containing hazardous gas;
 - (d) an exhaust tube through which the effluent may be flowed, the exhaust tube comprising sapphire and the exhaust tube being adapted to provide a non-circuitous and non-turbulent flow of effluent therethrough by being substantially absent projections or recesses (i) that alter the flow direction of the effluent to provide a circuitous flow of effluent through the exhaust tube, and (ii) that cause turbulence in the flow of the effluent through the exhaust tube; and
 - (e) a microwave energy applicator to couple microwaves to the effluent flowing through the exhaust tube to reduce the hazardous gas content of the effluent.